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To: Commissioner for Patents	Total Pages Sent: 5
Technology Center 1700	(including cover sheet)
Facsimile Number: 571-273-8300	Transmission Date: June 8, 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Chen, <i>et al.</i>	Docket No.:	TSM6283131RI
Serial No:	10/650,886	Art Unit:	1763
Date Filed:	August 28, 2003	Examiner:	George A. Goudreau
Title:	In-Situ Strip Process for Polysilicon Etching in Deep Sub-Micron Technology		

CERTIFICATION OF FACSIMILE TRANSMISSION

I hereby certify that the following papers are being transmitted by facsimile to the U.S. Patent and Trademark Office at 571-273-8300 on the date shown above:

- Certification of Facsimile Transmission (1 page)
- Supplemental Declaration for Reissue Patent Application (1 page)
- Information Disclosure Statement (2 duplicate pages)
- IDS Form PTO/SB/08a (1 page) citing 8 references

Respectfully submitted,

Judy A. Betts
Legal Assistant

Confirmation Respectfully Requested

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